



# IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

PATENT

In re patent application of: KEZUKA et al.

Serial No.: 09/856,358

Examiner:

Filed: 22 May 2001

Art Unit: 1746

For: ETCHING SOLUTION, ETCHED ARTICLE AND  
METHOD FOR ETCHED ARTICLE

Docket #: P07223US00/BAS

COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

TC 1700 MAIL ROOM

RECEIVED

FEB 28 2004

SIR:

Attached is:

- ..... a response after Final Rejection dated
- a response to the Office Action dated September 24, 2002
- ..... a Preliminary Amendment
- a Petition for an extension of time
- ..... Other:

Fees: For claims if required and/or other fees as shown below:

	NOW	Previously Paid For	Present Extra	Rate	\$
TOTAL CLAIMS				X \$ 18 =	
INDEP. CLAIMS				X \$ 84 =	
TOTAL OF ABOVE CLAIMS FEES =					
Reduction by ½ for <b>small entity status</b> of applicant					
SUBTOTAL =					
<input checked="" type="checkbox"/> Fee for extension of time (per attached Petition)					410.00
Other fee for					
<b>TOTAL OF ALL FEES =</b>					<b>\$410.00</b>

- .....  A check in the amount of \$ 410.00 is enclosed. If no check or an insufficient check is enclosed and a fee is due in connection herewith, the Commissioner is authorized to charge any fee or additional fee due in connection herewith to Deposit Account No. 12-0555.
- .....  In the event that a petition for extension of time is required to be submitted herewith and that a separate petition is not submitted herewith, applicant hereby petitions under 37 CFR 1.136(a) for an extension of time of as many months as are required to render this submission timely. Any fee is authorized above.

Respectfully submitted,

By: B. Aaron Schulman  
Registration No.: 31,877

Date: 24 February 2003

LARSON & TAYLOR, PLC • 1199 North Fairfax St. • Suite 900 • Alexandria, VA 22314



#6  
10  
3/3/03

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Patent

In re patent application of: KEZUKA et al.

Serial No.: 09/856,358

Examiner:

Filed: 22 May 2001

Art Unit: 1746

For: ETCHING SOLUTION, ETCHED ARTICLE AND  
METHOD FOR ETCHED ARTICLE

Docket #: P07223US00/BAS

**REQUEST FOR RECONSIDERATION**

Honorable Commissioner for Patents  
Washington, D. C.

SIR:

In response to the Official Action dated September 24, 2002, Applicants respond  
as follows:

RECEIVED  
FEB 28 2003  
TC 1700 MAIL ROOM

**REMARKS**

In the Official Action, there was a reference to the preliminary amendment filed on May 22, 2001, a copy of which is attached hereto. As is clear from the amendment, the amendment was made with regard to Claim 15 and not Claim 14. It is presumed that the amendment to Claim 15 was entered, but if not, Applicants request that the Examiner telephone the undersigned attorney to discuss the status of this claim.

In the Official Action, the Examiner rejected Claims 1, 15 and 16 under 35 U.S.C. §102(b) as being anticipated by the Li patent, US 5,783,495. This rejection is respectfully traversed for the reasons as stated below.

The Li et al reference cited by the Examiner in fact does not anticipate or make obvious the present claims. To the contrary, Li et al. merely provides a cleaning solution with an etch selectivity ratio of less than 4:1 (preferably 2:1, moreover 0.5:1) for a doped/deposited oxide:thermal/native oxide etch (see, column 4, lines 48-56 of Li et